Lecture 6w: Process Modules II

## Lecture 6: Process Modules II

- · Announcements:
- · HW#1 due today at 7:00 p.m.
- · HW#2 passed out and on line
- No office hours for me on Wednesday, 9/15, due to the BSAC Industrial Advisory Board Meeting
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- · Today:
- · Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 3, 6
  - **SExample MEMS fabrication processes**
  - **Oxidation**

- Evaporation
- -Sputter deposition
- -Chemical vapor deposition (CVD)
- Plasma enhanced chemical vapor deposition (PECVD)
- -Epitaxy
- -Atomic layer deposition (ALD)
- -Electroplating
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- · Last Time:
- · Going through Module 3 ... continue with this
- $\cdot$  ... then start going through Module 4